Atty. Docket No. 002187 USA C03/PDC/WF/DB
PATENT APPLICATION

PRELIMINARY AMENDMENT
Rule 53(b) Continuation of
U.S. Application No. 09/298,501

IN THE CLAIMS

Please cancel claims 1-95.

Please add the following new claims:

96. (New) An apparatus for inspection of a substrate, said apparatus comprising:

an illumination source illuminating said substrate;

first collection optics receiving light and outputting inspection signals;

a comparator calculating a difference between said inspection signals and a reference signal to identify locations on said substrate suspected of having defects thereupon based on a threshold, and outputting suspect location data;

second collection optics receiving light and outputting images according to said suspect location data; and

a defect classifier receiving and classifying said images.

97. (New) The apparatus of claim 96, wherein said illumination source is a laser.

98. (New) The apparatus of claim 96, wherein said first collection optics comprises a plurality of sensors.

99. (New) The apparatus of claim 98, wherein said first collection optics further comprises dark field collection optics.

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100. (New) The apparatus of claim 96, wherein said second collection optics comprises an imaging sensor.

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101. (New) The apparatus of claim 100, wherein said second collection optics further comprises bright field collection optics.

102. (New) The apparatus of claim 99, wherein said dark field collection optics includes a turret carrying a plurality of objectives thereupon.

103. (New) The apparatus of claim 101, wherein said bright field collection optics includes a turret carrying a plurality of objectives thereupon.

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104. (New) The apparatus of claim 96, further comprising an image processor receiving an output of said image sensor and outputting said images.

105. (New) The apparatus of claim 96, wherein said threshold is an adaptive threshold.